

PATENT APPLICATION

RESPONSE UNDER 37 CFR §1.116 EXPEDITED PROCEDURE TECHNOLOGY CENTER 1756

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masaaki KURIHARA et al.

Group Art Unit: 1756

Application No.: 10/614,345

Examiner:

J. RUGGLES

Filed: July 8, 2003

Docket No.: 123770

For:

PHASE MASK FOR FORMING DIFFRACTION GRATING, METHOD OF

FABRICATING PHASE MASK AND METHOD OF FORMING DIFFRACTION

GRATING

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In reply to the May 30, 2006, Office Action, please consider the following:

Amendments to the Specification;

Amendments to the Claims as reflected in the listing of claims; and

Remarks.